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		Filing Date	November 15, 1999
		Group	1763
(Use Several Sheets if Necessary)			

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
<i>L.D.AM</i>	A.	4,989,544	02/1991	Yoshikawa			
	B.	5,522,934	06/1996	Suzuki et al.			
	C.	5,810,932	09/1998	Ueda et al.			
	D.	6,132,552	10/2000	Donohoe et al.			
	E.						

Foreign Patent or Published Foreign Patent Application

Examiner Initial		Document No.	Publication Date	Country or Patent Office	Class	Sub-Class	Translation Yes No
	F.						
	G.						
	H.						
	I.						
	J.						
	K.						

Other Documents

Examiner Initial	No.	Author, Title, Place (e.g. Journal) of Publication, Date
<i>L.D.AM</i>	L.	Japanese Application No. 08255259, filed August 1996, entitled "SHALLOW MAGNETIC FIELD FOR IMPROVING PLASMA PROCESSING BY THE CIRCULATION OF ELECTRONS," by Michael Welch, Patent Abstracts of Japan, Vol. 1999, No. 7.
	M.	
	N.	
	O.	
	P.	
	Q.	
	R.	
	S.	
Examiner Initial		Date Considered
<i>A. Alejandro</i>		11/29/01

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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